Surface Group Modified Mxene Nano-flakes doping of Tungsten Disulfide Monolayer

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1. Characterization of Mxene



Figure S1. High-resolution X-ray photoelectron spectroscopy (XPS) spectra of F-Ti₃C₂T_x nano-flakes in Ti 2p region and its corresponding deconvoluted components.



Figure S2. High-resolution X-ray photoelectron spectroscopy (XPS) spectra of F- $Ti_3C_2T_x$ nano-flakes in C 1s region and its corresponding deconvoluted components.

2. Characterization of monolayer WS₂

The photoluminescence (PL) spectra of monolayer WS_2 on SiO_2/Si substrate were conducted through a WITec alpha 300 R system with an excitation wavelength of 532 nm at room temperature. In order to avoid heating and optical doping effect, the power of laser was kept as low as 10 μ W for the room temperature PL measurement.



Figure S3. (a) Optical image, (b) AFM image of a WS₂ flake on SiO₂/Si substrate measured at room temperature. (d) The AFM height measured along the dotted line in
(b). The scale bar in (a) and (b) is 2 μm, respectively.



Figure S4. Raman spectrum of a WS_2 flake on SiO_2/Si substrate measured at room temperature.



Figure S5. (a) PL mapping and (b) the corresponding PL spectrum of monolayer WS_2 excited by 523 nm laser. Inset: schematic drawing of the neutral exciton (X) and negative trion (X⁻). The scale bar in (a) is 2 μ m.

TMDCs	Dopant	PL enhancement factor ^a	References
WS ₂	F4TCNQ	~2.3	S1
WS ₂	fluorine plasma	~4.2	S2
WS ₂	choline plasma	~3.0	S3
MoS ₂	F4TCNQ	~3.2	S4
MoS ₂	TCNQ	~2.9	S4
MoS ₂	graphene	~2.0	S5
MoS ₂	gate voltage	~2.8	S 6
WS ₂	HATCN	~10	S7
WS ₂	Mxene	~5	This work

 Table S1. A brief summary of the PL enhancement in atomically thin transition metal

 dichalcogenides (TMDCs).^[1-6]

^aThe PL enhancement factor is defined as the ratio of the final integrated intensity of

modified TMDCs to the integrated intensity of pristine TMDCs.

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